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Cover

These images show TEM images of carbon nanoparticles synthesized by high pressure Ar + CH₄ plasma CVD process as a parameter of the gas pressure. The process controls nanoparticle generation and growth via the gas residence time which depends on the pressure. With increasing the gas pressure, the number of particles decreases and their size gradually increases. It indicates that the gas pressure is a key parameter to the nanoparticle synthesis using the process. (Sung Hwa HWANG *et al.*, Plasma and Fusion Research, Vol. 14, 4406115 (2019) <http://www.jspf.or.jp/>)

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